

PATENT ABSTRACTS OF JAPAN

(11)Publication number : **06-267408**

(43)Date of publication of application : **22.09.1994**

(51)Int.Cl.

H01J 9/14

G01B 21/30

G11B 9/00

H01J 37/28

H01L 41/09

(21)Application number : **05-072841**

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(22)Date of filing : **09.03.1993**

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(54) MANUFACTURE OF DETECTION PROBE FOR VERY SMALL DISPLACEMENT, DETECTION PROBE FOR VERY SMALL DISPLACEMENT, AND SCANNING PROBE MICROSCOPE AND INFORMATION PROCESSOR USING THESE

(57)Abstract:

PURPOSE: To provide a probe provided with a Fabry-Perot resonator, with which a bright interference fringe of high contrast can be provided.

CONSTITUTION: A probe is manufactured by utilizing semiconductor processing technique. A cantilever 4, on which a probe point 6 and an electrode 10 with a gap held for a transparent layer (substrate) 1 is formed on the transparent layer provided with a reflection surface 2 for partially reflecting measurement light 7a on one surface. A reflection surface 4 is formed on the surface of the cantilever 1 opposed to the reflection surface 2.

